TATES PATENT AND TRADEMARK OFFICE

Applicant:

Paul A. Farrar

JUN 2 4 2002

Examiner:

Serial No.:

09/944,983

Group Art Unit: 3723

Filed:

August 30, 2001

Docket: 1303.018US1

Title:

CHEMICAL MECHANICAL POLISHING SYSTEM AND PROCESS

INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents Washington, D.C. 20231

TECHNOLOGY CENTER TO RESTOO In compliance with the duty imposed by 37 C.F.R. § 1.56, and in accordance with 37 C §§ 1.97 et. seq., the enclosed materials are brought to the attention of the Examiner for consideration in connection with the above-identified patent application. Applicant respectfully requests that this Information Disclosure Statement be entered and the documents listed on the attached Form 1449 be considered by the Examiner and made of record. Pursuant to the provisions of MPEP 609, Applicant requests that a copy of the 1449 form, initialed as being considered by the Examiner, be returned to the Applicant with the next official communication.

Pursuant to 37 C.F.R. §1.97(b), it is believed that no fee or statement is required with the Information Disclosure Statement. However, if an Office Action on the merits has been mailed, the Commissioner is hereby authorized to charge the required fees to Account No. 19-0743 in order to have this Information Disclosure Statement considered.

The Examiner is invited to contact the Applicant's Representative at the below-listed telephone number if there are any questions regarding this communication.

Respectfully submitted,

PAUL A. FARRAR

By his Representatives,

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CERTIFICATE UNDER 37 CFR 1.8: The undersigned hereby certifies that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail, in an envelope addressed to: Commissioner of Patents, Washington, D.C. 20231, on this day of June, 2002.

Name



TECHNOLOGY CENTER ROTO

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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We are transmitting herewith the following attached items (as indicated with an "X"):

A return postcard.

<u>X</u> <u>X</u> An Information Disclosure Statement (1 pg.), Form 1449 (2 pgs.), and copies of 24 cited references.

Please consider this a PETITION FOR EXTENSION OF TIME for sufficient number of months to enter these papers and please charge any additional required fees or credit overpayment to Deposit Account No. 19-0743.

SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A.

P.O. Box 2938, Minneapolis, MN 55402 (612-373-6900)

Reg. No. 38,377

CERTIFICATE UNDER 37 CFR 1.8: The undersigned hereby certifies that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail, in an envelope addressed to: Commissioner for Patents, Washington,

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